

| | Type | Hits | Search Text |
|----|------|-------|---|
| 1 | IS&R | 0 | ("cleaning same (wafer or substrate) same post same plasma same etching").PN. |
| 2 | BRS | 28944 | (CLEANING SAME (WAFER OR SEMICONDUCTOR OR SUBSTRATE)) |
| 3 | BRS | 598 | ((POST SAME PLASMA) SAME (ETCH OR ETCHING)) |
| 4 | BRS | 47 | "non splash" |
| 5 | BRS | 3333 | (SCRUB\$5 SAME BRUSH) |
| 6 | BRS | 0 | (((((POST SAME PLASMA) SAME (ETCH OR ETCHING))) SAME ((CLEANING SAME (WAFER OR SEMICONDUCTOR OR SUBSTRATE))))) same ("NON SPLASH") |
| 7 | BRS | 0 | (((((POST SAME PLASMA) SAME (ETCH OR ETCHING))) SAME ((CLEANING SAME (WAFER OR SEMICONDUCTOR OR SUBSTRATE))))) same ((SCRUB\$5 SAME BRUSH)) |
| 8 | BRS | 0 | (((((POST SAME PLASMA) SAME (ETCH OR ETCHING))) SAME ((CLEANING SAME (WAFER OR SEMICONDUCTOR OR SUBSTRATE))))) and ("NON SPLASH") |
| 9 | BRS | 1 | (((((POST SAME PLASMA) SAME (ETCH OR ETCHING))) SAME ((CLEANING SAME (WAFER OR SEMICONDUCTOR OR SUBSTRATE))))) AND ((SCRUB\$5 SAME BRUSH)) |
| 10 | BRS | 16 | "5174816" |
| 11 | BRS | 90367 | 438/\$.ccls. |
| 12 | BRS | 28942 | 134/\$.ccls. |
| 13 | BRS | 14178 | 216/\$.ccls. |
| 14 | BRS | 3 | (((((POST SAME PLASMA) SAME (ETCH OR ETCHING))) SAME ((CLEANING SAME (WAFER OR SEMICONDUCTOR OR SUBSTRATE))))) AND (134/\$.CCLS.) |
| 15 | BRS | 5 | (((((POST SAME PLASMA) SAME (ETCH OR ETCHING))) SAME ((CLEANING SAME (WAFER OR SEMICONDUCTOR OR SUBSTRATE))))) AND (216/\$.CCLS.) |

| | DBs | Time Stamp | C o m m e n t s | E r r o r D e f i n i t i o n | E r r o r s |
|----|------------------------|---------------------|--------------------------------------|---|----------------------------|
| 1 | USPAT; JPO; Derwent | 2000/07/19 13:56 | | | 0 |
| 2 | USPAT; JPO; Derwent | 2000/07/18 13:55 | | | 0 |
| 3 | USPAT; JPO; Derwent | 2000/07/18 13:57 | | | 0 |
| 4 | USPAT; JPO; Derwent | 2000/07/18 14:00 | | | 0 |
| 5 | USPAT; JPO; Derwent | 2000/07/18 14:04 | | | 0 |
| 6 | USPAT; JPO; Derwent | 2000/07/18 14:04 | | | 0 |
| 7 | USPAT; JPO; Derwent | 2000/07/18 14:04 | | | 0 |
| 8 | USPAT; JPO; Derwent | 2000/07/18 14:04 | | | 0 |
| 9 | USPAT; JPO; Derwent | 2000/07/18 14:07 | | | 0 |
| 10 | USPAT; JPO; Derwent | 2000/07/18 14:07 | | | 0 |
| 11 | USPAT; JPO; Derwent | 2000/07/18 15:34 | | | 0 |
| 12 | USPAT; JPO; Derwent | 2000/07/18 14:23 | | | 0 |
| 13 | USPAT; JPO; Derwent | 2000/07/18 14:24 | | | 0 |
| 14 | USPAT; JPO; Derwent | 2000/07/18 14:26 | | | 0 |
| 15 | USPAT; JPO; Derwent | 2000/07/18 14:31 | | | 0 |

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|----|------|--------|--|
| 16 | BRS | 16 | (((((POST SAME PLASMA) SAME (ETCH OR ETCHING))) SAME ((CLEANING SAME (WAFER OR SEMICONDUCTOR OR SUBSTRATE)))) AND (438/\$.CCLS.)) |
| 17 | BRS | 42 | ((((POST SAME PLASMA) SAME (ETCH OR ETCHING))) SAME ((CLEANING SAME (WAFER OR SEMICONDUCTOR OR SUBSTRATE)))) |
| 18 | BRS | 239 | 438/906.ccls. |
| 19 | BRS | 625 | 438/974.ccls. |
| 20 | BRS | 3045 | ((ETCH SAME POST) OR (ETCHING SAME POST)) |
| 21 | BRS | 395322 | ((AME OR (ETCH SAME POST)) OR (ETCHING SAME POST) OR CLEANING) |
| 22 | BRS | 221 | ((ETCH SAME POST) OR (ETCHING SAME POST)) SAME CLEANING) |
| 23 | BRS | 5 | ((438/906.CCLS.) AND (((ETCH SAME POST) OR (ETCHING SAME POST)) SAME CLEANING))) |
| 24 | BRS | 3 | ((438/974.CCLS.) AND (((ETCH SAME POST) OR (ETCHING SAME POST)) SAME CLEANING))) |
| 25 | BRS | 8 | ((PLANARIZATION OR SCRUBBING OR POLISHING) SAME "POST CLEANING") |
| 26 | BRS | 708 | 438/692 |
| 27 | BRS | 11 | ((438/692) AND ((SCRUB\$5 SAME BRUSH))) |
| 28 | BRS | 220 | ((ETCH SAME Plasma) SAME (DEPOSIT OR RESIDUE)) SAME (REMOVING OR CLEANING OR REMOVAL) |
| 29 | BRS | 85 | ((ETCH SAME POST) SAME (DEPOSIT OR RESIDUE)) SAME (REMOVING OR CLEANING OR REMOVAL) |
| 30 | BRS | 200 | (((((ETCH SAME PLASMA) SAME (DEPOSIT OR RESIDUE)) SAME (REMOVING OR CLEANING OR REMOVAL))) NOT (((ETCH SAME POST) SAME (DEPOSIT OR RESIDUE)) SAME (REMOVING OR CLEANING OR REMOVAL)))) |
| 31 | BRS | 269 | "brush box" |
| 32 | BRS | 4 | ("BRUSH BOX" SAME WAFER SAME CLEANING) |
| 33 | BRS | 0 | ("BRUSH BOX" SAME WAFER SAME (plasma adj etching)) |

| | DBs | Time Stamp | C o m m e n t s | E r r o r D e f i n i t i o n | E r r o r s |
|----|------------------------|---------------------|--------------------------------------|---|----------------------------|
| 16 | USPAT; JPO; Derwent | 2000/07/18 14:41 | | | 0 |
| 17 | USPAT; JPO; Derwent | 2000/07/18 15:18 | | | 0 |
| 18 | USPAT; JPO; Derwent | 2000/07/18 15:18 | | | 0 |
| 19 | USPAT; JPO; Derwent | 2000/07/18 15:19 | | | 0 |
| 20 | USPAT; JPO; Derwent | 2000/07/18 15:20 | | | 0 |
| 21 | USPAT; JPO; Derwent | 2000/07/18 15:20 | | | 0 |
| 22 | USPAT; JPO; Derwent | 2000/07/18 15:21 | | | 0 |
| 23 | USPAT; JPO; Derwent | 2000/07/18 15:21 | | | 0 |
| 24 | USPAT; JPO; Derwent | 2000/07/18 15:30 | | | 0 |
| 25 | USPAT; JPO; Derwent | 2000/07/18 15:31 | | | 0 |
| 26 | USPAT; JPO; Derwent | 2000/07/18 15:34 | | | 0 |
| 27 | USPAT; JPO; Derwent | 2000/07/18 18:04 | | | 0 |
| 28 | USPAT; JPO; Derwent | 2000/07/18 16:30 | | | 0 |
| 29 | USPAT; JPO; Derwent | 2000/07/18 16:30 | | | 0 |
| 30 | USPAT; JPO; Derwent | 2000/07/18 17:45 | | | 0 |
| 31 | USPAT; JPO; Derwent | 2000/07/19 14:13 | | | 0 |
| 32 | USPAT; JPO; Derwent | 2000/07/19 14:27 | | | 0 |
| 33 | USPAT; JPO; Derwent | 2000/07/19 14:28 | | | 0 |

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|----|------|------|---|
| 34 | BRS | 0 | ("BRUSH BOX" SAME WAFER SAME plasma) |
| 35 | BRS | 2 | ("ETCH BACK" SAME WEB) |
| 36 | BRS | 0 | ("tungsten ETCH BACK" SAME WEB) |
| 37 | BRS | 1 | ("TUNGSTEN ETCH BACK" SAME ETCHING SAME PLASMA) |

| | DBs | Time Stamp | C o m m e n t s | E r r o r D e f i n i t i a l i z a t i o n | E r r o r s |
|----|------------------------|---------------------|--------------------------------------|--|----------------------------|
| 34 | USPAT; JPO; Derwent | 2000/07/19 14:33 | | | 0 |
| 35 | USPAT; JPO; Derwent | 2000/07/19 14:35 | | | 0 |
| 36 | USPAT; JPO; Derwent | 2000/07/19 14:35 | | | 0 |
| 37 | USPAT; JPO; Derwent | 2000/07/19 14:36 | | | 0 |